

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Confirmation No.: 2987

Takushi YOSHIDA, et. al.

Date: August 23, 2007

Serial No.: 10/541,507

Group Art Unit: 1763

Filed: July 8, 2005

Examiner: Sylvia MacARTHUR

For: SUBSTRATE PROCESSING SYSTEM, SUBSTRATE PROCESSING
APPARATUS, PROGRAM AND RECORDING MEDIUM

VIA EFS-WEB
 Mail Stop Amendment
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT
REMARKS/ARGUMENT

This Response is filed in reply to the Restriction Requirement dated July 30, 2007.

Applicant elects the invention of Group I, identified as claims 40-76, drawn to a substrate processing system.

Applicant reserves the right to file a divisional application directed to the subject matter covered in the non-elected claims.

Early and favorable consideration of the present application is earnestly solicited.

If this communication is filed after the statutory time period had elapsed and no separate Petition is enclosed, the Commissioner for Patents is petitioned, under 37 C.F.R. §1.136(a), to extend the time for filing a response to the outstanding Office Action by the number of months which will avoid abandonment under 37 C.F.R. §1.135. The fee under 37 C.F.R. § 1.17 should be charged to our Deposit Account No. 15-0700.

Respectfully submitted,

THIS CORRESPONDENCE IS BEING
 SUBMITTED ELECTRONICALLY
 THROUGH THE UNITED STATES
 PATENT AND TRADEMARK OFFICE
 EFS FILING SYSTEM
 ON AUGUST 23, 2007


 MAX MOSKOWITZ
 Registration No.: 30,576
 OSTROLENK, FABER, GERB & SOFFEN, LLP
 1180 Avenue of the Americas
 New York, New York 10036-8403
 Telephone: (212) 382-0700